

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Tetsuo SHIMOMURA et al.
App. No	:	10/598,717
Filed	:	September 8, 2006
For	:	POLISHING PAD AND SEMICONDUCTOR DEVICE MANUFACTURING METHOD
Examiner	:	Alvin J. Grant
Art Unit	:	3723
Conf No.	:	9262

AMENDMENT ACCOMPANYING RCE**Mail Stop RCE**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed November 12, 2008, please reconsider the present application in light of the following amendments and comments

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 8 of this paper.